

Notice of References Cited	Application/Control No. 10/810,406	Applicant(s)/Patent Under Reexamination BURDORF ET AL.	
	Examiner Brian Q. Le	Art Unit 2624	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Martin et al. "X-Ray Lithography – An Overview", I.E.E.E. Volume 81, Issue 9, September 1993 Pages: 1249 - 1274.
	V	
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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